

Docket No.: 1268-093A



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Moshe FINAROV

U.S. Patent Application No. 09/626,793

Filed: July 26, 2000

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: Confirmation No. 8657
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: Group Art Unit: 2851
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: Examiner: D. Esplin

For: APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR PROCESS
CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A METHOD FOR
USE THEREOF

PATENT

RECEIVED
AUG 13 2003
TECHNOLOGY CENTER 2800

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

Sir:

The following amendments and remarks are submitted in response to the Official Action
dated May 13, 2003.

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